



GP/2877

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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Bruce et al. Examiner: Turner, S.
Serial No.: 09/386,112 Group Art Unit: 2877
Filed: August 30, 1999 Docket No.: AMDA.261PA
Title: DUAL-DIFFERENTIAL INTERFEROMETRY FOR SILICON DEVICE
DAMAGE DETECTION

#10/Response
4/10/01

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this communication is being deposited in the United States Postal Service, as first class mail, in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on March 30, 2001.

By:

Eric J. Curtin

OFFICE ACTION RESPONSE

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated January 30, 2001, please consider the following remarks.

Remarks

Favorable reconsideration of this application is requested in view of the following remarks. For the reasons set forth below, Applicant respectfully submits that the claimed invention is allowable over the cited references.

The Office Action dated January 30, 2001, indicated that claims 1-16 stand rejected under 35 U.S.C. §112, first paragraph; and claims 1,2,7 and 9-15 stand rejected under 35 U.S.C. §103(a) as being unpatentable over *Marx et al.* (U.S. Patent No. 5,880,838).

In regard to the Section 112, first paragraph rejection of claims 1-16, Applicant submits that the Specification and claims are clearly sufficient to enable one skilled in the art to make and use the invention. In regard to how the light is reflected from the die, Applicant submits that reflections from various defects, surfaces and other portions in the die can make up the reflection. For example, page 8, lines 9-16, page 10, lines 18-23 and FIG. 2, item 232 at surface 231 are all